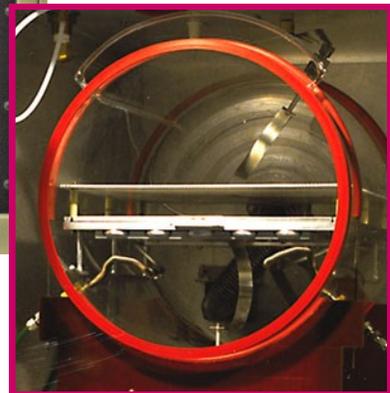
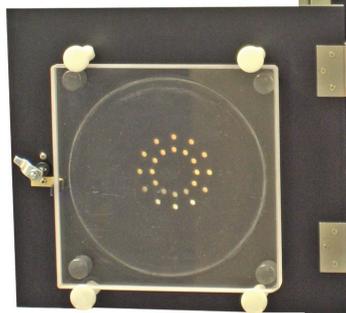
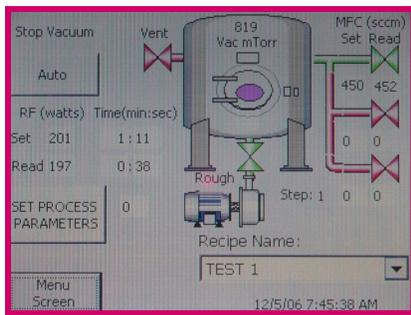


SCE-150 Plasma System

Siemens S7-200 Series
"Touch Panel" Control
Pass word protected



Front - to - Back laminar gas flow ensures uniform multi-directional cleaning

Planar Parallel Plate

De-scum chamber for removing residues from photo masks and other resist contaminated parts!

Anatech's plasma systems are CFC and effluent free, operator and environmentally safe, easily operated.

SCE-150 Barrel Plasma System

Control System: "Touch-Panel" Display

Siemens S7-200
Programmable Logic Controller LCD Display:
Pressure display
Gas flow with mass flow controllers (2)
Dual gas input
Process time remaining
Safety interlocks

Power Requirements:

120 VAC 20A 50/60 HZ

Options:

220 VAC

Control System:

Options:

3rd Gas channel
Data logging
Capacitance manometer
Temperature sensor
Throttle valve
Nitrogen backfill
Slow pump and particle reduction
Operational Light Array

Dimensions:

System comes in standard 19 inch half rack
36 inch high x 23 inch wide x 27 inch deep
250 lbs Crated weight (estimated)

Reactor Chamber:

Quartz Chamber 10" Diameter x 18" Long
Planar Electrodes 2 (1-Hot, 1-Ground)
Electrode Dimensions: 9" x 16"
Front Loading
View port on front door with UV shield

Vacuum System:

23 CFM Standard
Main Vacuum Valve system controlled
6 feet of 1.500 " ID Vacuum line
Oxygen Service, Class "B" Preparation

RF Power Source:

0-600 Watt, 13.56 MHz
Forward and reflected power reading
Automatic Matching Network

Options:

1000 Watt 13.56 MHz supply

Vacuum System:

Options:

Corrosive service
Mist eliminator
Oil filtration

CALL ANATECH USA TO DISCUSS YOUR APPLICATION

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